1. Scope

This specification applies to PQC bright light inspection of wafers.

2. Reference Documents

2.1 None.

3. Table of Contents

4. Equipment

4.1 Bright light projector SOS-1.
4.2 Irvine Optical Systems automated inspector.

5. Method of inspection

5.1 Place the jig containing the wafers to be inspected on the cassette stage of the Irvine inspector. When the cassette is properly placed, the red LED on the corner of the stage will turn green.

5.2 Press the "R" key to run the inspection program. (If an "Insufficient House Vacuum" error occurs, make sure the vacuum wand on the table is replaced properly in its holder so that the vacuum flow is shut off. If the error does not disappear, call EES.) Choose Program auto1 by pressing "1". The inspector will scan the cassette.

5.3 To start, enter the slot number you desire. The wafer will load and the stage will raise the wafer into the upper light, and begin rotation. You may stop the rotation by pressing the ROTATE/PAUSE key, or change its speed and direction by pressing the INC, DEC, and REV keys. The lights are controlled by the LITE1 (overhead light) and LITE2 (side light) keys. LITE3 is inactive. The angle of the wafer may be changed with the trackball, and the back side of the wafer may be seen with the mirror.

5.4 Press NEXT to inspect the next wafer, or "S" to stop inspecting.

5.5 To inspect wafers manually, use the bright light projector SOS-1.